



S O S G R O U P

Rigaku TXRF 300Fab

SN ER72007

Vintage 2008

Rigaku TXRF 300Fab
Serial nr ER72007
Vintage 5-2008
located still in Fab (EU)
300, 200, 150mm

TXRF analysis can gauge contamination in all fab processes, including cleaning, litho, etch, ashing, films, etc. The TXRF 300 Fab can measure elements from Na through U with a single-target, 3-beam X-ray system and a liquid nitrogen-free detector system.

The TXRF 300 Fab includes Rigaku's patented XYθ sample stage system, an in-vacuum wafer robotic transfer system, and new user-friendly windows software. All of these contribute to higher throughput, higher accuracy and precision, and easy routine operation. Optional Sweeping TXRF software enables mapping of the contaminant distribution over the wafer surface to identify "hot spots" that can be automatically re-measured at higher precision.



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SYSTEM : TXRF 300Fab
ORDER No.: BW57-2013
POWER : 200VAC 3 ϕ 60A 50Hz
SERIAL No. : ER72007
DATE : May.2008



RIGAKU INDUSTRIAL CORPORATION
MADE IN JAPAN

Solutions on Silicon BV

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